

Part Number

Customer

| Category | Parameter | Specification | Measurement Method |
|---------------|--|---|--|
| OverallWafer | 1.0 Diameter | 100.00 +/- 0.50 mm | WaferVendor |
| | 2.0 Primary Flat Orientation | <110> +/- 1 degree | Wafer Vendor |
| | 3.0 Primary Flat Length | 32.50 +/- 2.50 mm | Wafer Vendor |
| | 4.0 Secondary Flat Orientation | semi std or none | Wafer Vendor |
| | 5.0 Overall Thickness | 525.00 +/- 5.00 um | Guaranteed by Process |
| | 6.0 Total Thickness Variation (TTV) | <5.00um | Guaranteed by Process |
| | 7.0 Bow | <40.00um | Guaranteed by Process |
| | 8.0 Warp | <40.00um | Guaranteed by Process |
| | 9.0 Edge Exclusion | 5 mm | Guaranteed by Process |
| HandleSilicon | 10.0 Handle Growth Method | CZ | Wafer Vendor |
| | 11.0 Handle Orientation | <100> +/- 0.5 degree | Wafer Vendor |
| | 12.0 Handle Thickness | 440.00 +/- 5.00 um | Guaranteed by Process |
| | 13.0 Handle Doping Type | N | Wafer Vendor |
| | 14.0 Handle Dopant | Arsenic | Wafer Vendor |
| | 15.0 Handle Resistivity | < 0.005 | Wafer Vendor |
| | 16.0 Backside Finish | Lapped and etched with no oxide and lasermark | Wafer Vendor |
| DeviceSilicon | 17.0 Device Growth Method | FZ | Wafer Vendor |
| | 18.0 Device Orientation | <100> +/- 0.5 degree | Wafer Vendor |
| | 19.0 Nominal Thickness | 85.00 +/- 2.00 um | FTIR, 100% 9-Pt (note3). No offset added to device |
| | 20.0 Distance to device silicon edge from wafer edge | <= 2mm | Guaranteed by Process |
| | 21.0 Device Doping Type | N | Guaranteed by Process |
| | 22.0 Device Dopant | Phosphorous | Guaranteed by Process |
| | 23.0 Device Resistivity | 2800 - 5200 Ohmem | Wafer Vendor |
| | 24.0 Voids | none | Guaranteed by Process, SAM inspection |
| | 25.0 Haze | none | Guaranteed by Process, Bright LIght inspection |
| | 26.0 Scratches | none | Guaranteed by Process, Bright LIght inspection |

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| Shipping Details | Wafer per box : | Max 25 | |
| | Packaging : | Taped Polypropylene Wafer Box Empak, Ultrapak, 100.00mm Antistatic Double Bagging | |
| | Lot Shipment Data | Device Thickness Bow / Warp Data Handle and SOI Thickness | |



Explanatory Notes 1. Microscope inspection performed using microscope scan as below. 5x objective.

2. All bright light inspections performed exclude all wafer area outside the edge exclusion defined in Overall Wafer, Edge Exclusion. High intensity bright lamp inspection as per ASTM F523.

3. 9 point measurement are as shown in the diagram below:



Additional Information